

EEMF6382 - Introduction to MEMS

[EEMF 6382](#) ([MECH 6347](#) and [MSEN 6382](#)) Introduction to MEMS (3 semester credit hours) Study of micro-electro-mechanical devices and systems and their applications. Microfabrication techniques and other emerging fabrication processes for MEMS are studied along with their process physics. Principles of operations of various MEMS devices such as mechanical, optical, thermal, magnetic, chemical/biological sensors/actuators are studied. Topics include: bulk/surface micromachining, LIGA, microsensors and microactuators in multiphysics domain. (3-0) T